

Serial No. 09/843,023 Atorney Docket No. 40013-0002

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application: Becky Losee

Serial No.: 09/843,023

Filed: April 26, 2001

For: METHODS FOR ETCHING SILICON

**TRENCHES** 

Confirmation No. 7229

Group Art Unit: 2823

Examiner: J. Maldonado

Thanger

3/11/03

Commissioner for Patents Washington, D.C. 20231

Box Non-Final Response

Sir:

ECHROLOGY CENTER 2800

## AMENDMENT AND REQUEST FOR RECONSIDERATION UNDER 37 C.F.R. §§ 1.111 & 1.115

In response to the Office Action dated November 21, 2002, Applicant requests reconsideration of this application in light of the following amendments and remarks.

03/12/2003 ASMITH

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01-FC:3203 02 FU: 111" 84,00 CH 10%, 17 EE

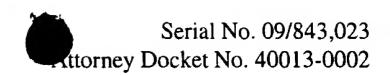
I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D. C. 20231, on this 21st day of

February 2003.

Signed:

Dated:

2/21/2003



## IN THE TITLE

Please substitute the following Title for the originally filed Title. A copy of the title showing the amendment is attached as Appendix A.

METHODS FOR ETCHING DEEP SILICON TRENCHES WITH A HIGH DEPTH UNIFORMITY

2/21/2003

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